### Simulation of RF MEMS switching time

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# **RF MEMS switches**

- Advantages
  - High isolation
  - Low insertion loss
- Disadvantages
  - High driving voltage
  - Low switching speed
- Applications
  - Wireless communication
  - Radar systems

# **Project Outline**

- Analytical solution
- Model
- Results and observations
- Conclusion

## **Analytical solution-1**

• Governing equations (without damping)

$$m\ddot{x} + kx = \in \frac{AV^2}{2(g-x)^2} \to t = \int_0^{g_0} \sqrt{\in \frac{AV^2x}{m(g-x)} - \frac{kx^2}{m}} dx^{-1}$$
$$g = g_0 + td \in r$$

# **Analytical solution-2**

• Governing equations (with damping)

$$\begin{split} m\ddot{x} + c\dot{x} + kx &= F\\ c &= \alpha m + \beta k \quad (Rayleigh \ damping)\\ m\ddot{x} + \beta k\dot{x} + kx &= F, when \ \alpha &= 0\\ \ddot{u} + \mu \dot{u} + u &= \frac{\gamma v^2}{(1+\delta-u)^2}; \ u &= \frac{x}{g^0}, \dot{u} = g0. \sqrt{m/k}. \dot{x}\\ \gamma &= \frac{\varepsilon A}{2kg0^3}, \mu = \beta \sqrt{k/m} \end{split}$$

• Solutions are evaluated using oneDdyne.m

### Model-1



- A thin micromechanical bridge suspended over a dielectric layer (εr=7.5)
- Air gap of 0.9µm and a dielectric layer of 0.1µm

# Vstep= 5V, $\beta = 0 \mu s$



Switching time is observed to be 8µs (analytical value: 3.96 µs)

# Vstep= 5V, $\beta$ =0.1 $\mu$ s



Switching has not occurred with 50µs.

# Vstep= 10V, $\beta = 0\mu s$



Switching time is observed to be 5  $\mu$ s(analytical 2.4  $\mu$ s)

# Vstep= 10V, $\beta$ =0.1 $\mu$ s



### Model 2 : Vstep= 5V , $\beta = 0\mu s$



Switching time is observed to be 6  $\mu$ s (with half thickness)

#### **Observations**

- Damping parameter (β)
  As β increases, switching time increases
- Applied voltage (Vstep)
  - As Vstep increases, switching time decreases

### Conclusion

- One degree of freedom model of capacitive switch is solved analytically.
- Results obtained from COMSOL have been compared against the analytical solutions.
- Variation of switching time with respect to damping parameter, input step voltage and beam configuration has been studied.

#### References

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